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Notice of Allowability	Application No.	Applicant(s)	
	10/720,325	HSU, PING	
	Examiner	Art Unit	
	Asok K. Sarkar	2891	
The MAILING DATE of this communication a All claims being allowable, PROSECUTION ON THE MERITS herewith (or previously mailed), a Notice of Allowance (PTOL- NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATEN' of the Office or upon petition by the applicant. See 37 CFR 1.	S IS (OR REMAINS) CLOSED in 85) or other appropriate common T RIGHTS. This application is	n this application. If not included unication will be mailed in due could be mailed in due could be the could be applied in the could be applied to the could be applied by th	rse. THIS
1. \boxtimes This communication is responsive to <u>RCE filed 2/6/200</u>	<u>06</u> .	,	
2. The allowed claim(s) is/are <u>1-22</u> .			
 3. Acknowledgment is made of a claim for foreign priorit a) All b) Some* c) None of the: 1. Certified copies of the priority documents here. 	nave been received.		
2. Certified copies of the priority documents h	• •	•	
 Copies of the certified copies of the priority International Bureau (PCT Rule 17.2(a)). 	documents have been receive	d in this national stage application	from the
* Certified copies not received:		•	
Applicant has THREE MONTHS FROM THE "MAILING DAT noted below. Failure to timely comply will result in ABANDO THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		a reply complying with the require	ements
4. A SUBSTITUTE OATH OR DECLARATION must be su INFORMAL PATENT APPLICATION (PTO-152) which			CE OF
5. CORRECTED DRAWINGS (as "replacement sheets")	must be submitted.		
(a) \square including changes required by the Notice of Drafts	person's Patent Drawing Review	v (PTO-948) attached	
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date	·	•	
(b) ☐ including changes required by the attached ExaminePaper No./Mail Date	ner's Amendment / Comment or	r in the Office action of	
Identifying indicia such as the application number (see 37 CF each sheet. Replacement sheet(s) should be labeled as such			k) of
 DEPOSIT OF and/or INFORMATION about the de attached Examiner's comment regarding REQUIREME 	eposit of BIOLOGICAL MATI NT FOR THE DEPOSIT OF BIO	ERIAL must be submitted. Note DLOGICAL MATERIAL.	the
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Attachment(a)			•
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. Notice of In	formal Patent Application (PTO-15	i2)
2. Notice of Draftperson's Patent Drawing Review (PTO-94		ummary (PTO-413),	
3. ☑ Information Disclosure Statements (PTO-1449 or PTO/S		/Mail Date Amendment/Comment	:
Paper No./Mail Date <u>2/6/2006</u> 4. Examiner's Comment Regarding Requirement for Deposit	sit 8. ⊠ Examiner's	Statement of Reasons for Allowan	ıce
of Biological Material	9. 🗌 Other		
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DETAILED ACTION

Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after allowance or after an Office action under *Ex Parte Quayle*, 25 USPQ 74, 453 O.G. 213 (Comm'r Pat. 1935). Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, prosecution in this application has been reopened pursuant to 37 CFR 1.114. Applicant's submission filed on February 6, 2006 has been entered.

Allowable Subject Matter

- 2. Claims 1 22 are now allowed.
- 3. The following is an examiner's statement of reasons for allowance:

Claims 1 – 14 recite, inter alia, a method of fabricating a trench device structure comprising the steps of forming a second conductive layer overlying the first conductive layer in the deep trench, herein the second conductive layer is lower than the surface of the semiconductor substrate and a portion of the second conductive layer is isolated from the semiconductor substrate by the second portion of the collar insulating layer.

The art of record does not disclose or anticipate the above limitation in combination with other claim elements nor would it be obvious to modify the art of record so as to form a device including the above limitation.

Claims 15 – 22 recite, inter alia, a method of fabricating a trench device structure with a single – side buried strap, comprising the steps of performing a tilt ion

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implantation on undoped polysilicon or amorphous silicon layer, wherein a portion of the undoped polysilicon or amorphous silicon layer in the deep trench is not implanted, selectively wet etching the undoped polysilicon or amorphous silicon layer, thereby exposing the underlying lining layer, sequentially etching the exposed lining layer and the contiguous collar insulating layer expose a portion of the semiconductor substrate using the doped polysilicon or amorphous silicon layer as a mask, and removal of the remaining lining layer and the doped polysilicon or amorphous silicon layer. The art of record does not disclose or anticipate the above limitation in combination with other claim elements nor would it be obvious to modify the art of record so as to form a device including the above limitation.

Conclusion

- 1. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."
- 2. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Asok K. Sarkar whose telephone number is 571 272 1970. The examiner can normally be reached on Monday Friday (8 AM- 5 PM).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, William B. Baumeister can be reached on 571 272 1722. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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3. Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Asok K. Sarkar May 9, 2006

Primary Examiner